

M.E. PRODUCTION ENGINEERING FIRST YEAR SECOND SEMESTER EXAMINATION - 2024

Subject: Nano-Technology & Micro-Machining (PT)

Time : Three Hours
Full Marks: 100

Use Separate Answer Script for Each Part

PART I

(40 for Part I)

Answer Any Two Questions

Q1.

- a) What is a Micro Electro Mechanical system (MEMS)? Describe the essential elements of MEMS. 6
- b) Explain the following processes in respect of micro manufacturing: i) Lithography, ii) Electro plating, (4 + 5)
- c) Discuss with suitable examples how 'Surface Micro-machining' is different from 'Bulk Micro- machining'. 5

Q2.

- a) Make a comparative analysis of Chemical & Physical Vapour deposition techniques.
- b) With suitable diagrams explain the following deposition processes: i) Casting, and ii) Sputtering
- c) Explain in detail how mirror surface finish can be achieved by ELID grinding.

4+8+8

Q3.

- a) State the objectives of nano- metrology. Differentiate between Industrial and Research oriented nano-metrology.
- b) With suitable diagrams explain the principle of Scanning Electron Microscopy.
- c) Define Nano-material. What is a one dimensional Nano-material? State some industrial applications of nano-materials.

6+7+7

[Turn over

MASTER OF PRODUCTION ENGG. EXAMINATION, 2024
(2nd Semester)
SUBJECT – NANO-TECHNOLOGY AND MICRO-MACHINING

Time: Three hours

Marks: 100

Use separate answer-script for each part.

PART- II (Marks: 60)

Answer any *three* questions

- | | | |
|----|--|----|
| 1. | (a) What are the different basic approaches for Micro-Fabrication? Define “Nano-Technology” and “Micro-Machining”. | 10 |
| | (b) Classify various micro machining and nano finishing process. | 10 |
| 2. | (a) Describe Electrochemical Micro-Machining (EMM) process with the aid of a schematic diagram of all the major sub-systems. | 10 |
| | (b) Represent an equivalent circuit model of inter electrode gap in EMM. | 5 |
| | (c) On the basis of various characteristics, differentiate between EMM and ECM. | 5 |
| 3. | (a) What is Micro-EDM? Differentiate between Micro-EDM and conventional EDM. | 8 |
| | (b) Classify types of Micro-EDM. | 4 |
| | (c) Describe some additional devices utilized for in-situ fabrication of microelectrodes with micro-EDM setup. | 8 |
| 4. | (a) What are the advantages of Electron Beam Machining (EBM) over other micro machining processes? | 6 |
| | (b) Explain the basic working principal of EBM with a schematic diagram. | 8 |
| | (c) Explain Electron Beam Drilling method. | 6 |
| 5. | (a) Identify Focused Ion Beam machining (FIB) for different applications during micro fabrication. | 6 |
| | (b) Explain FIB milling and its scanning strategy during micro machining. | 8 |
| | (c) Identify different applications of FIB machining. | 6 |